



NOTES

1. MATERIAL: UVFS
2. CLEAR APERTURE: >90%CA
3. SURFACE QUALITY(S1,S2): 60/40(S/D)
4. WAVEFRONT ERROR(RMS): $\lambda/4@633\text{ nm}$ (SUBSTRATE)
5. PARALLELISM(S1,S2): <3 arcmin
6. ARROW POINTS TO THE FILTERING COATING
7. COATING:
 FILTERING(S1): $T_{\text{avg}} > 90\%$, $T_{\text{abs}} > 85\% @ 505-800\text{ nm}, 45^\circ\text{ AOI}$
 $R_{\text{avg}} > 95\%$, $R_{\text{abs}} > 90\% @ 380-475\text{ nm}, 45^\circ\text{ AOI}$
 AR COATING(S2): $R_{\text{abs}} < 2\% @ 505-800\text{ nm}, 45^\circ\text{ AOI}$

DRAWING PROJECTION			LBTEK			
	NAME	DATE	DM20-490LP			
DRAWN	LZHOU	JUL./30th/24	LONGWAVE DICHOIC MIRROR $\varnothing 50.8\text{ mm} \times 5\text{ mm}, 490\text{ nm}$			
APPROVAL	WCHENG	JUL./30th/24	MATERIAL	WEIGHT	SCALE	REV
FOR INFORMATION ONLY NOT FOR MANUFACTURING PURPOSES			UVFS	22.3 g	1:1	A